OLYMPUS®

Your Vision, Our Future

300mm WAFER LOADER

AL120-12

SERIES

NEW

300mm Compatible wafer loader & microscope system

300 mm wafer

Top surface macro

Back surface macro

1 cassette One cassette

AL120-LMB12-LP

AL120-LMB12-F

With attention to wafer safety, the AL120 series is committed to enhancing the essence of operations in back-end process and providing improving yield and productivity improvement.

Easy operation

- The AL120-12 series emphasizes usability through features including fully customizable Inspection mode and device design that takes into account operability tailored for exclusive use in back-end process.
- The AL120 also provides you the system with FOSB for exclusive use.

The highest system reliability and inherited system performance

- The AL120-12 series allows safety and automated micro inspection of 300 mm wafers, with keeping the high level of reliability and safety provided in the AL110 series.
- The AL120 enables a transfer of both warped wafer and thin wafer with OLYMPUS safety and reliable handling system.
- The AL120 provides you easy operation and high visibility with the optimized position for macro inspection and the friendly control panel.

Dedicated macro illumination unit (optional)

- Users can select the macro illumination to provide optimal illumination to inspect for particles, scratches, film undulations and defocus.
- The combination of a high-intensity metal halide light source and fiber optics allows illumination of a full-surface of 300 mm wafer with cold-light illumination.

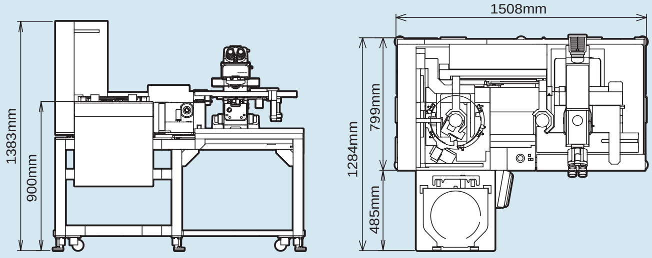
Dedicated macro illumination unit

Specifications

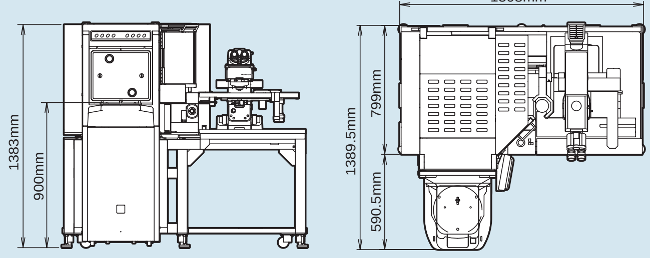
	AL120-LMB12-F	AL120-LMB12-LP
Wafer size	300mm (SEMI M1.15 t=775µm) 200 mm (Optional)	
Standard type of cassette	FOSB (Front Opening Shipping Box) SEMI:M31-0999 Standard	FOUP (Front Opening Unified Pods) SEMI:E47.1-0200 Standard FIMS-FOSB, FOSB
Number of cassette	1 Cassette (load /unload on the same route)	
Height of cassette loading position	900mm	
Load port	Not available	Available
Transfer modes	Top macro inspection, back macro inspection, micro inspection	
Inspection mode	Sequential or Sampling	
Wafer alignment	Non-contact centering	
Wafer handling method	Robot arms with vacuum pickup	
Compatible microscope	Semiconductor wafer inspection microscope MX61L	
Utility	AC100V-120V, 220-240V 3.0/1.7A 50/60Hz Vacuum -67~-80Kpa	
Stage	XY manual stage with vacuum attraction /360 degree rotatable function	
Weight (excluding the microscope)	Approximately 270Kg	Approximately 360Kg

Dimensions

AL120-LMB12-F



AL120-LMB12-LP



OLYMPUS CORPORATION has obtained ISO9001/ISO14001

Illumination devices for microscope have suggested lifetimes. Periodic inspections are required. Visit our Website for details.

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